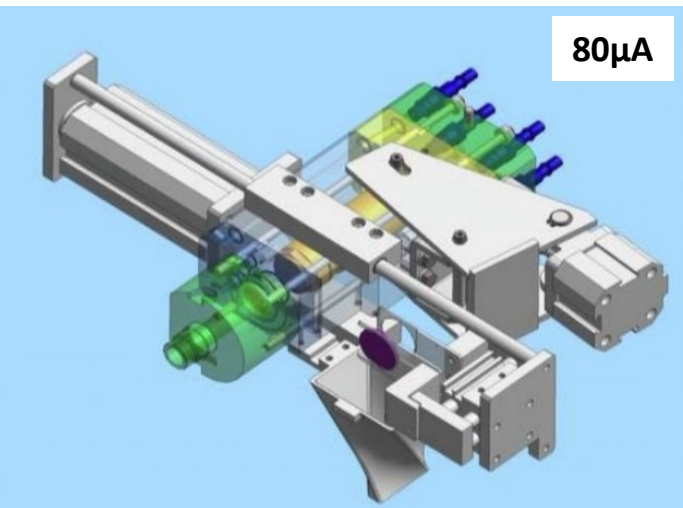
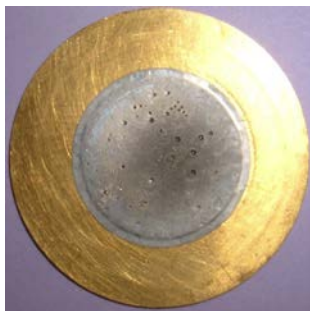


Experimental set-up for thermal resistance at interface measurements

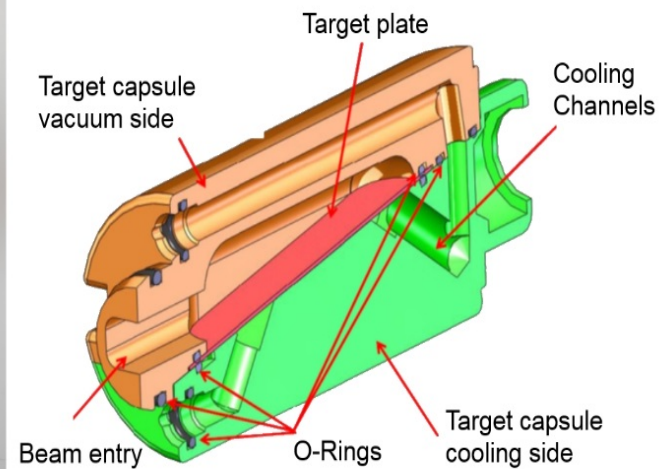
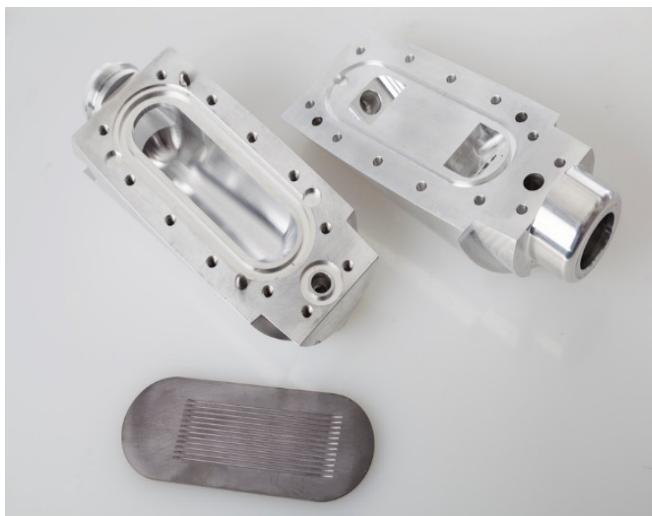
SARA CISTERNINO, HANNA SKLIAROVA, MATTEO GOBBO,
CARLOS ROSSI ALVAREZ, ALESSANDRO ZANON, JUAN ESPOSITO

Cyclotron solid target station

TEMA target prototype
St.Orsola Hospital, Bologna

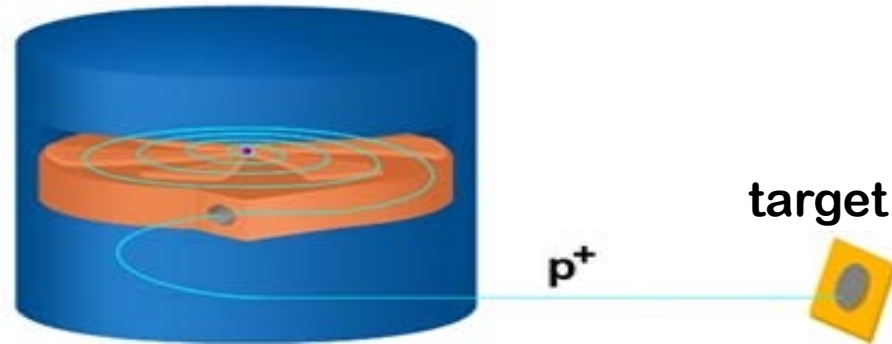


TR19 target of
Advanced Cyclotron
Systems Inc.



$300\mu\text{A}$

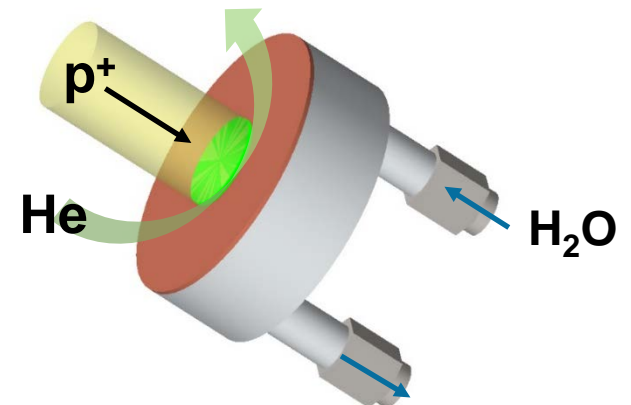
Solid target station: a technical design challenge



New high performance cyclotrons -> High radioisotopes yields -> heat power removal eng. issues

↳ High heat power density hitting the target

Heat dissipation system

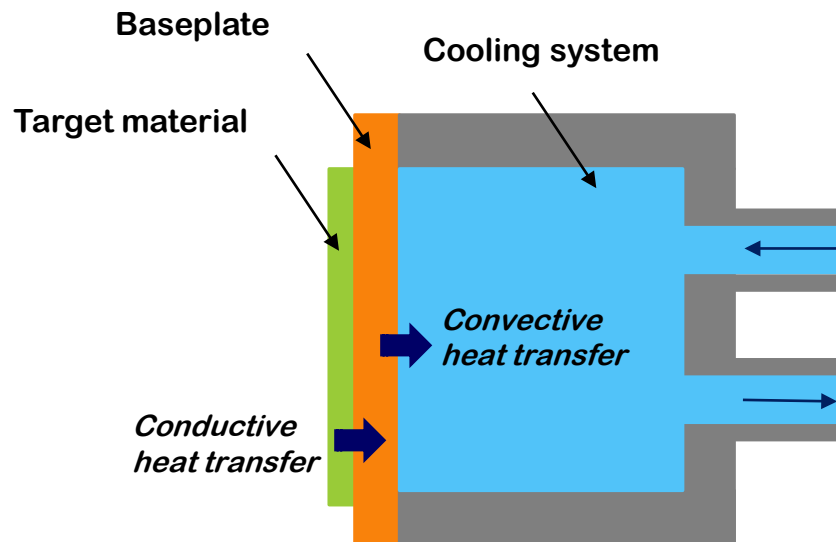


How to dissipate the heat power?

State of art: radioisotope solid target system

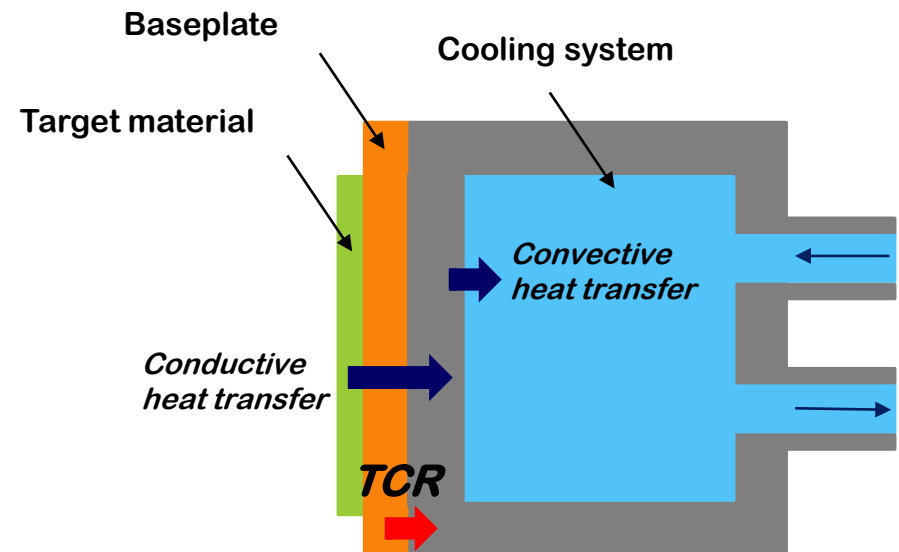
Open cooling system conf.

- ✓ Direct more efficient cooling
- X Potential loss of coolant accident (LOCA)



Closed cooling system conf.

- ✓ No water losses → higher safety
- ✓ Possible different cooling sink geometry
- X Target temperatures affected by Thermal Contact Resistance at interface



LARAMED target system : main design goal



Main target station design input :

- Heat power removal : 30 kW
- Possible beam hitting configurations:
- $E_{\max} = 70 \text{ MeV}$, $I_{\min} = 100 \text{ } \mu\text{A}$
- $E_{\min} = 40 \text{ MeV}$, $I_{\max} = 750 \text{ } \mu\text{A}$

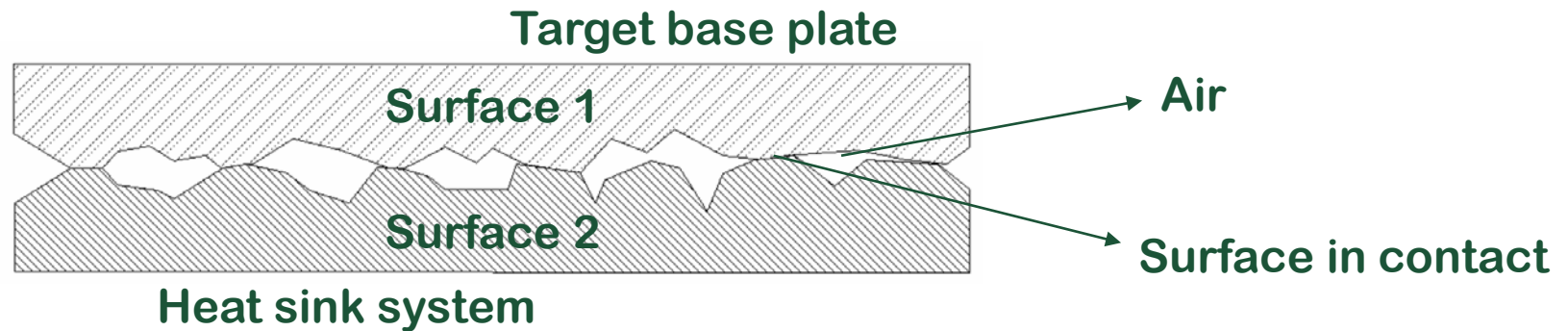
Average beam power density of 1 kW/cm^2 on the target
(reference target area spot size: 30 cm^2)

High power cyclotron solid target station

Preferred configuration: closed cooling system

Thermal Contact Resistance at interface

The main problem to work out: Thermal Contact Resistance (TCR) at interface



Thermal Contact Resistance (TCR) depends on:

- materials
- surface roughness
- contact pressure
- oxidation level

Thermal Contact Resistance at interface

Analytical model*

$$TCC = 1,55 k_s \left(\frac{m}{\sigma}\right) \left(\frac{\sqrt{2}p}{mE'}\right)^{0,94}$$

TCC: Thermal contact conductance [$\text{W m}^{-2} \text{K}^{-1}$]

k_s : harmonic average of thermal conductivity of the materials [$\text{W m}^{-1} \text{K}^{-1}$]

σ : RMS surface contact roughness [m]

m : slope of material asperity $f(\sigma)$

p : contact pressure [Pa]

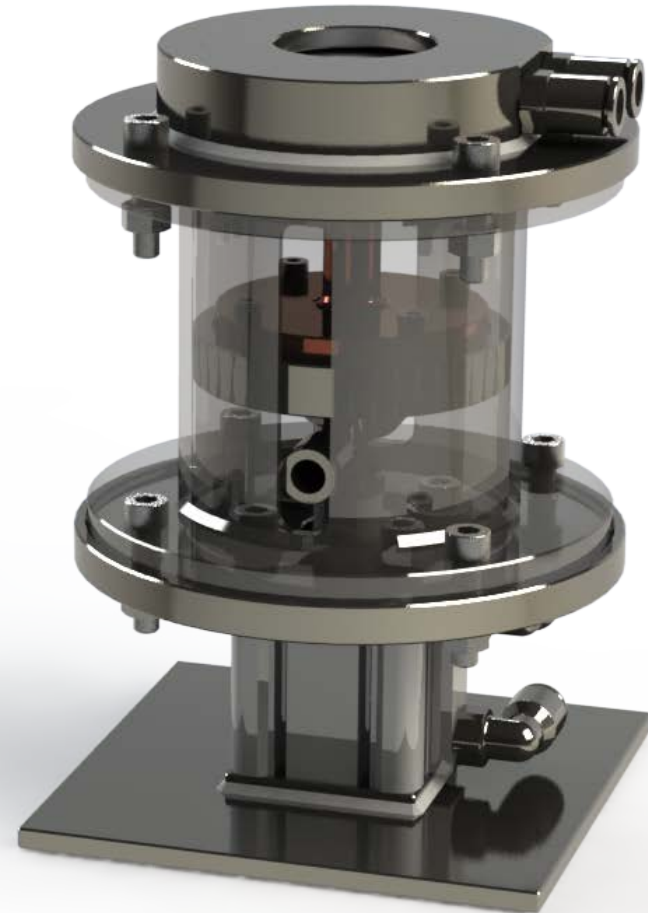
E' : Young Modulus of the materials [Pa]

* A. Dall'Occhio, A. Bertarelli et al., "LHC Collimators: un modello agli elementi finiti per l'analisi termostrutturale", Associazione italiana per l'analisi delle sollecitazioni (AIAS), XXXVI Convegno Nazionale

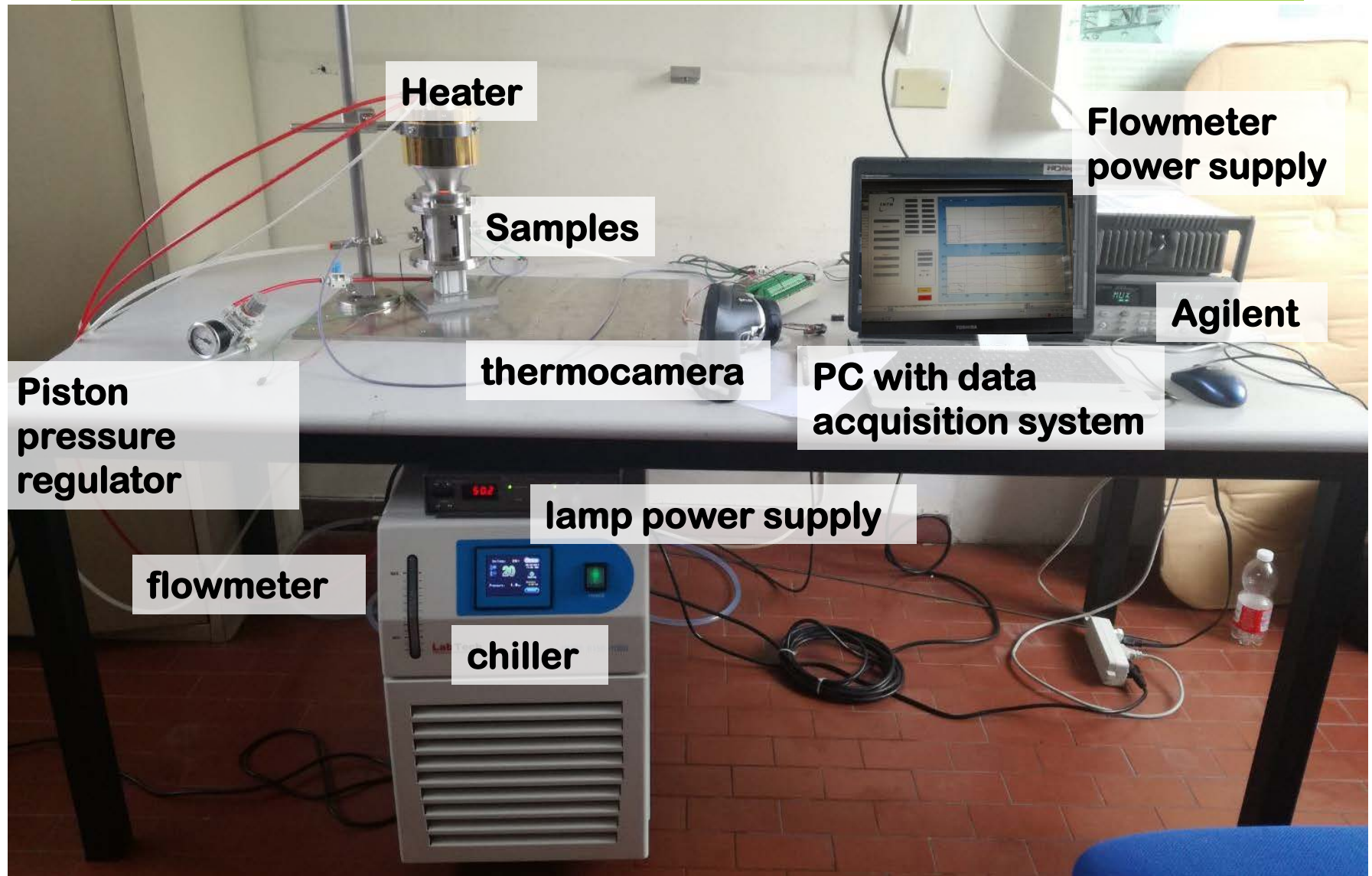
Experimental set-up for TCR measurement

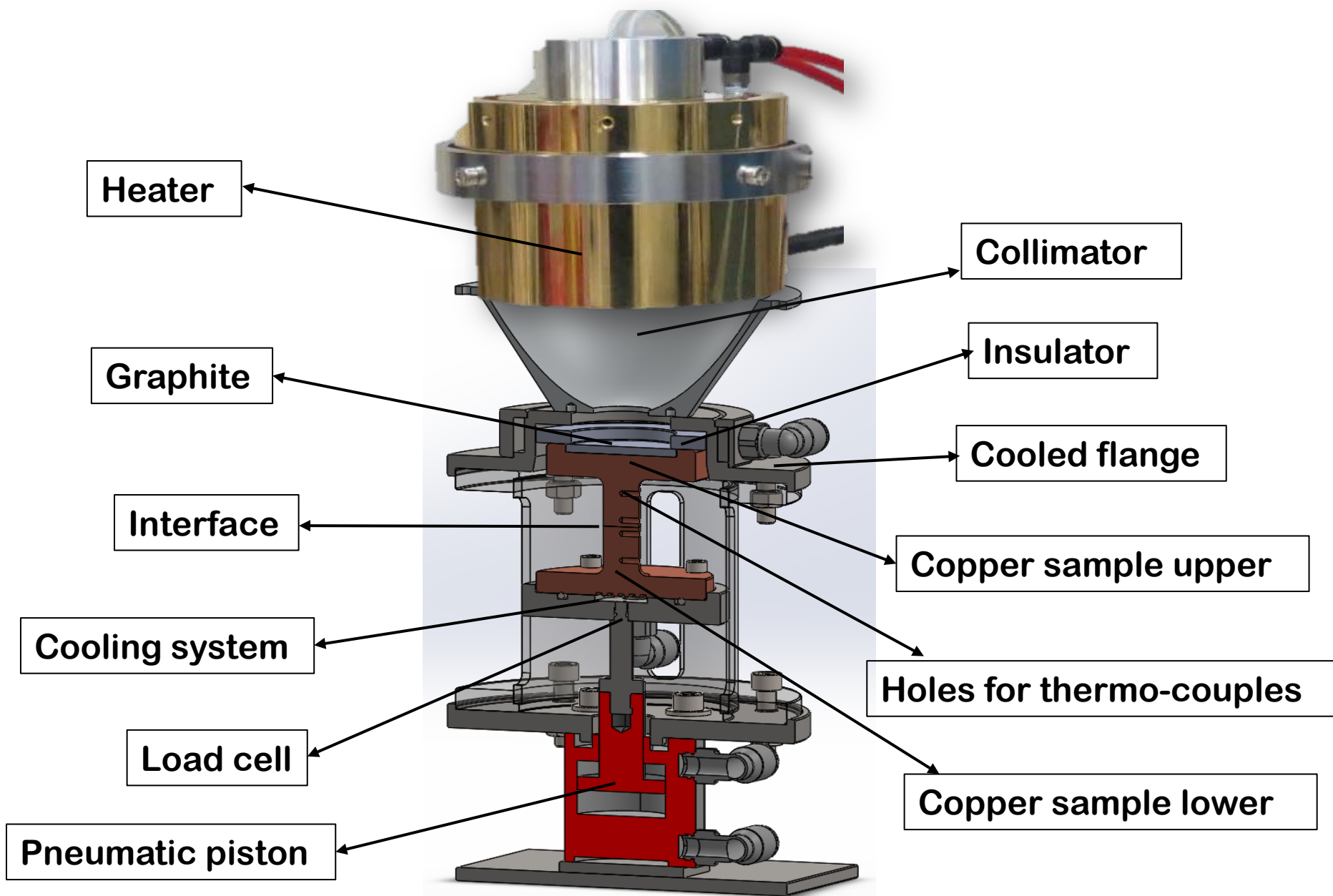
Experimental set-up designed in order to measure Thermal Contact Resistance (TCR) for real systems

- different target/heat sink materials (Cu-OFE /Al alloys, other materials)
- different surface finishing (turning, grinding, lapping)
- different contact pressures (1.3 – 4.2 MPa)
- different surface oxidation level



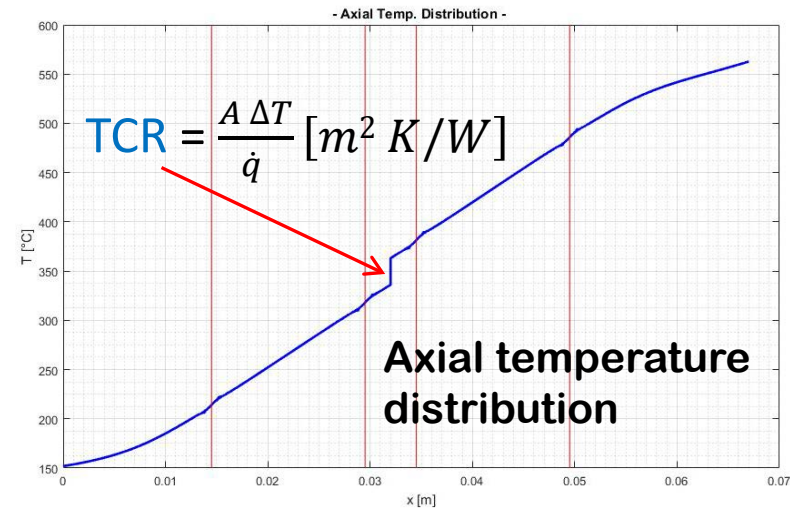
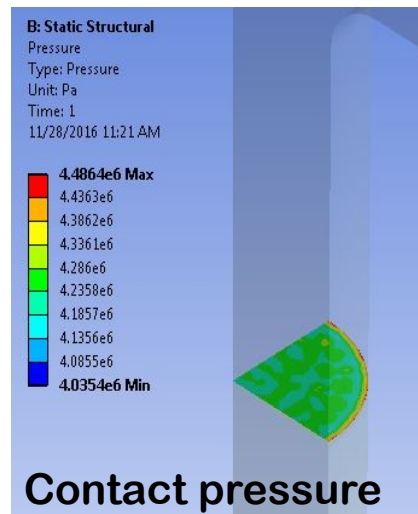
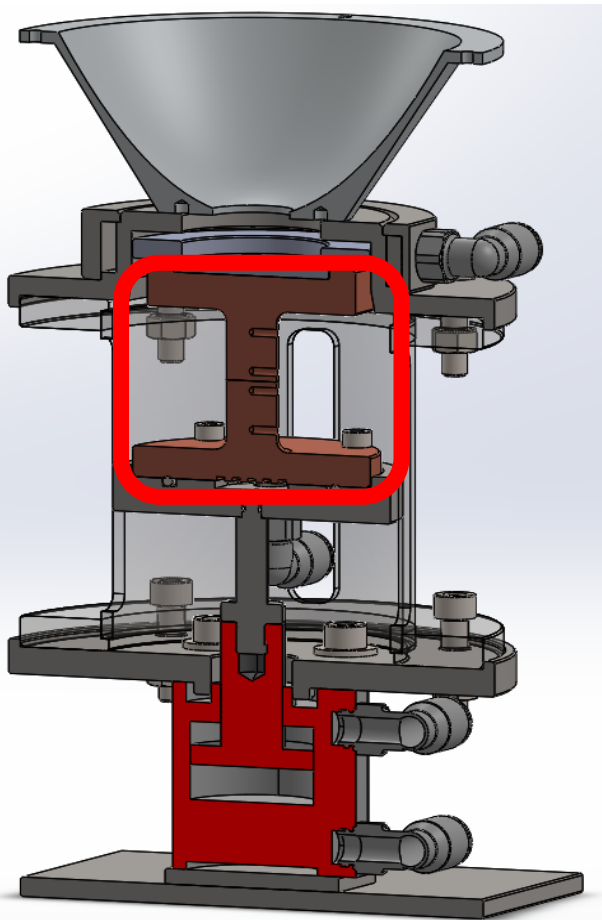
Experimental set-up for TCR measurement





Samples geometry chosen

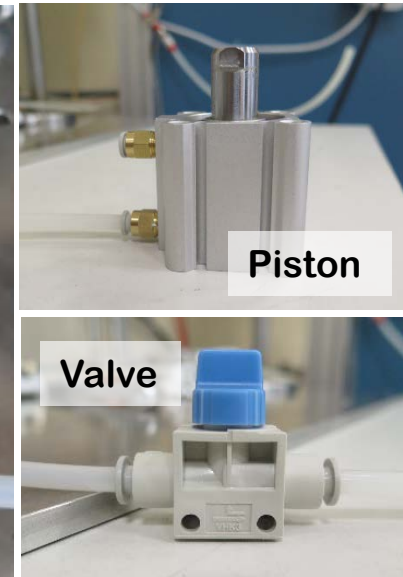
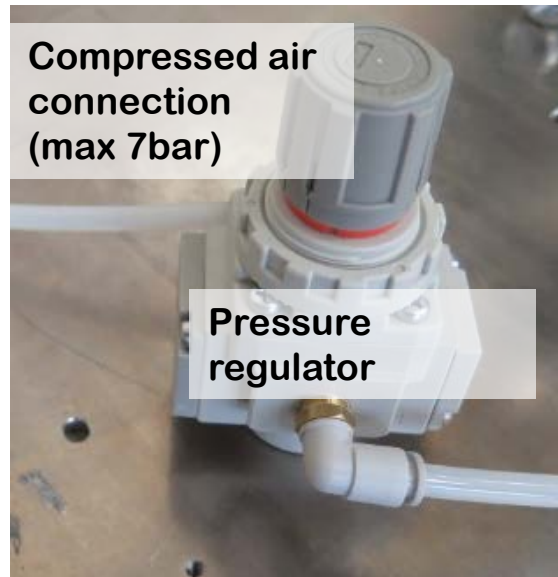
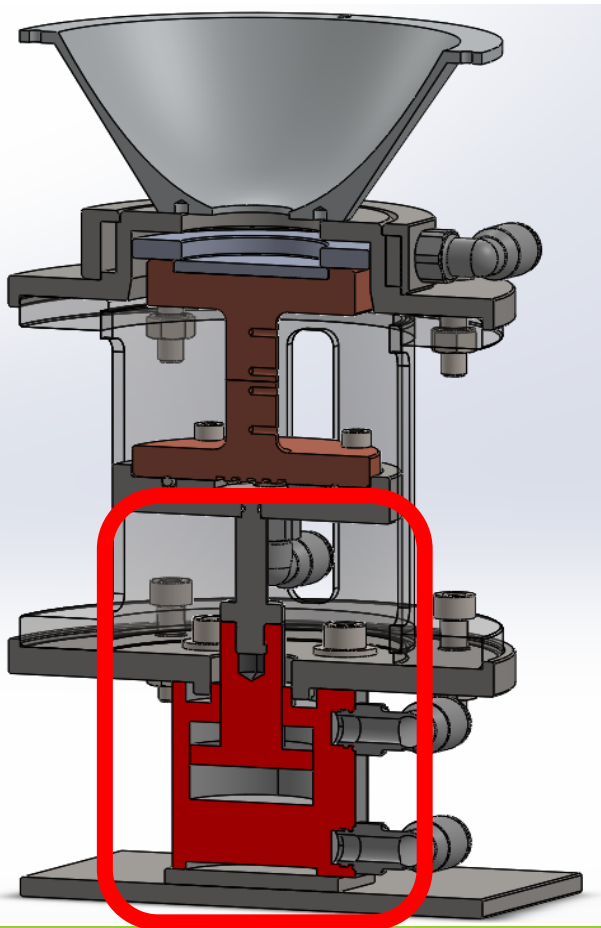
- ANSYS thermal and structural FEM to get:
 - a uniform contact pressure at interface
 - a linear temperature distribution along the axis



- 4 K-Thermocouples
- Different surface treatments at interface

Pressure load system

- Compressed air driven pneumatic piston to tune the samples contact pressure

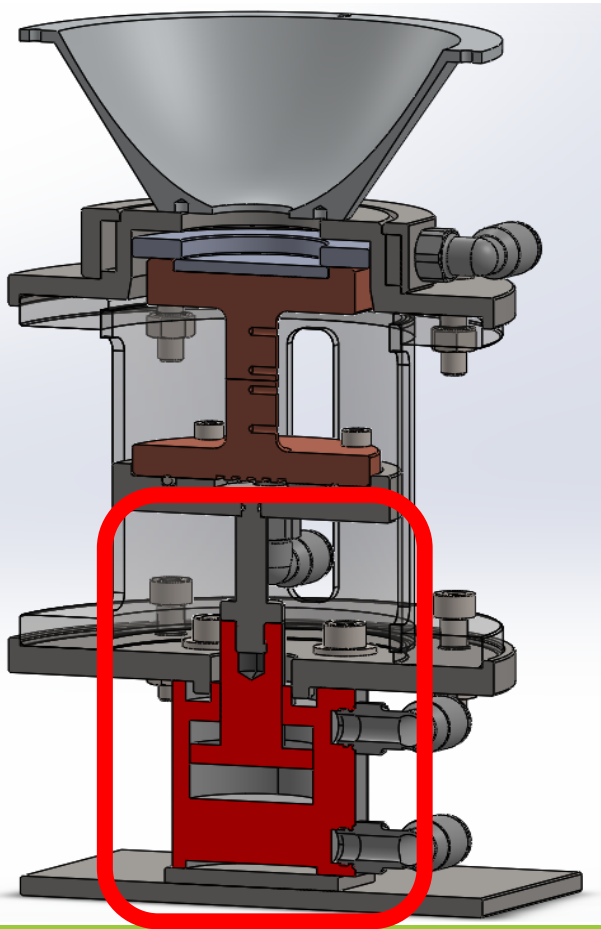


- Load cell to measure the force used to keep the samples pressed



FX1901 Compression Load Cell

Air pressure – Contact pressure loads ranges



Air pressure [bar]	Contact pressure [Mpa]
2	1,3
3	1,9
4	2,5
5	3,1
6	3,6
7	4,2

Heat source - IR lamp main data

Main Electric parameters

- Power supply voltage: 0-100 V
- Absorbed Power: 1 kW

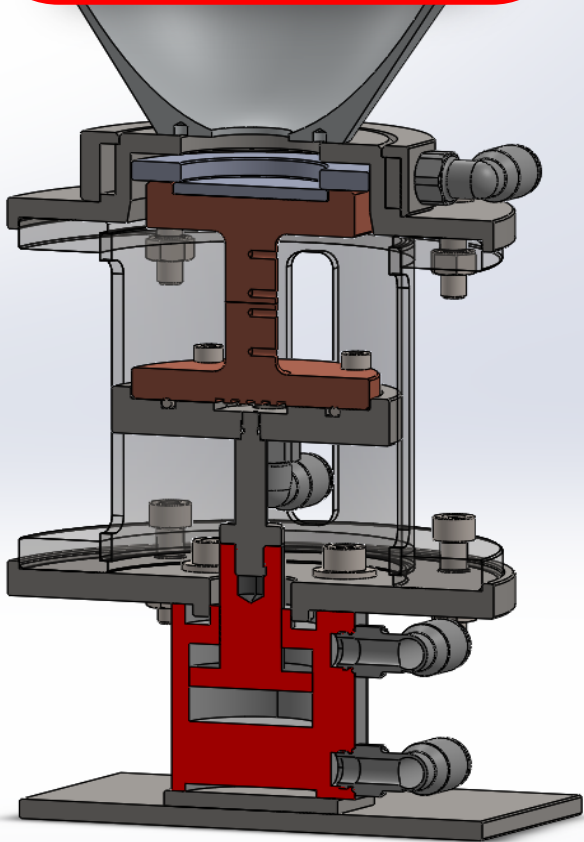
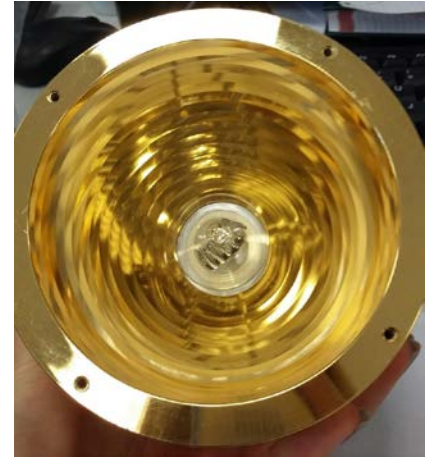
IR output range

- Beam spot $\varnothing 15$ mm

Declared beam power density

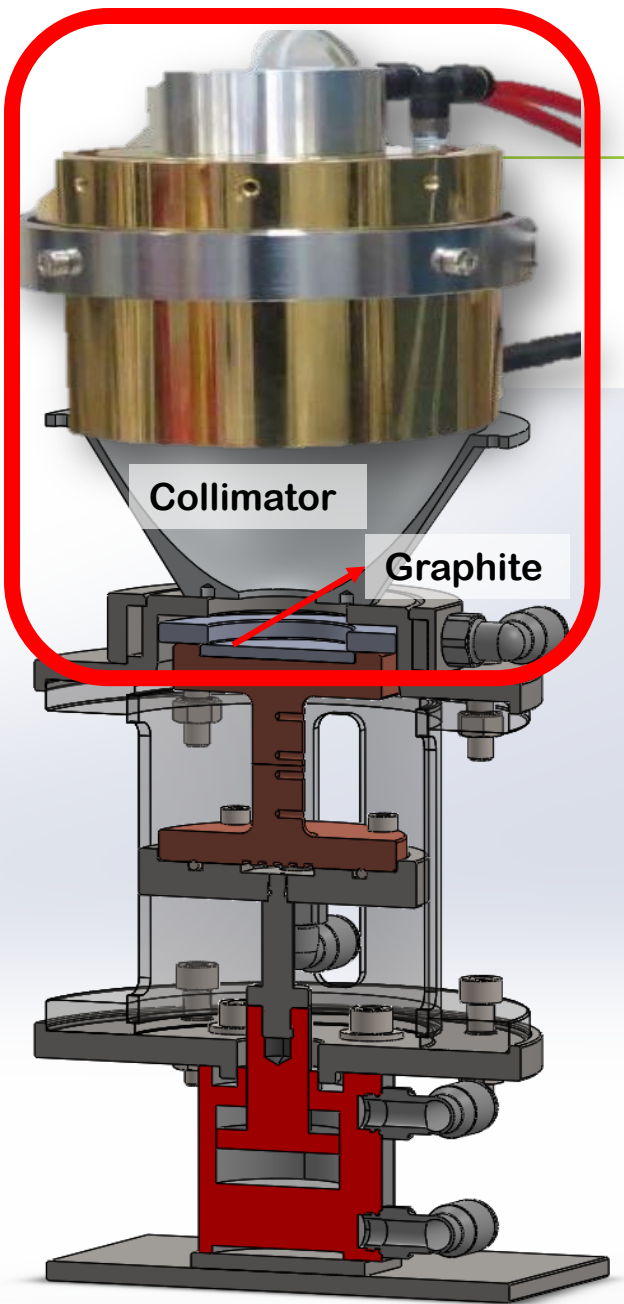
- approximately 124 W/cm^2

Max. heating temperature: $1000 \text{ }^\circ\text{C}$

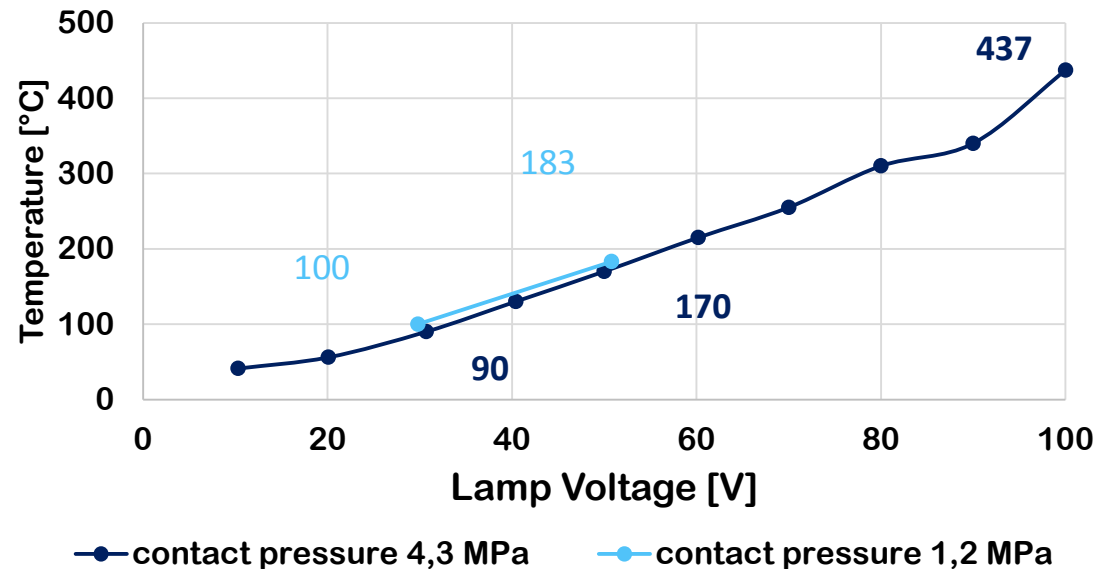


Heat source- IR lamp

- Use of collimator to focus the spot and protect the eyes
- Use of graphite disk to absorb better IR (Cu and Al reflect IR light)



Estimation of graphite T vs Lamp voltage



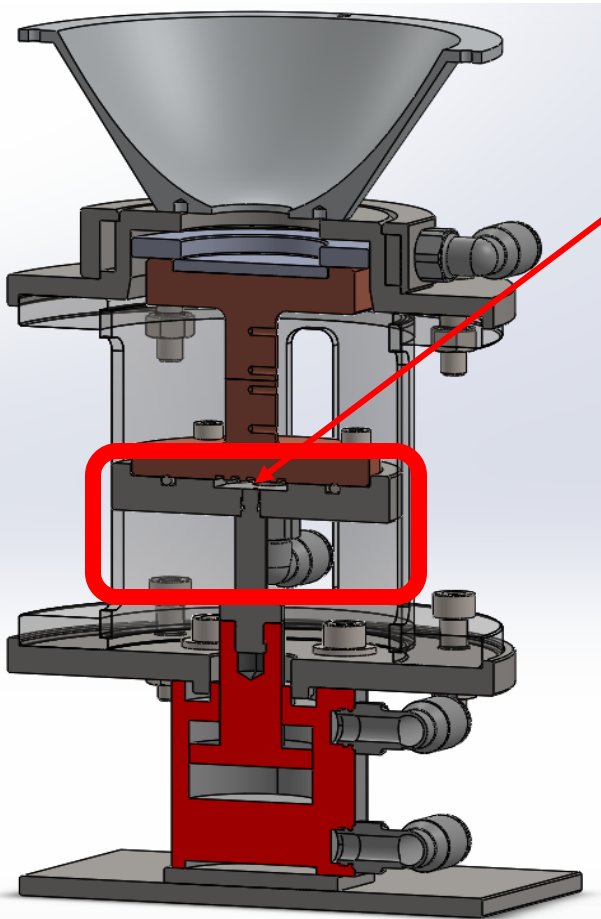
Water cooling

➤ Chiller

➤ Cooling chamber in contact with the lower sample

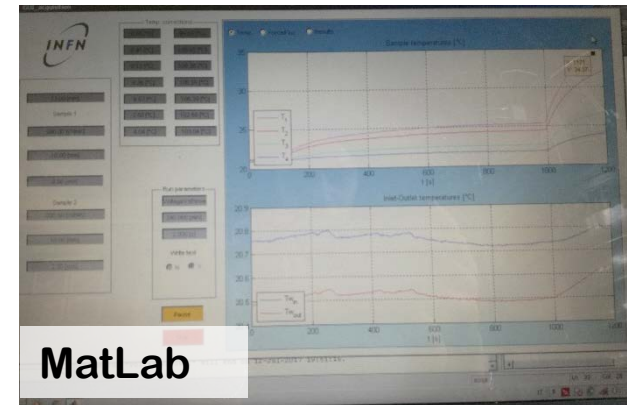
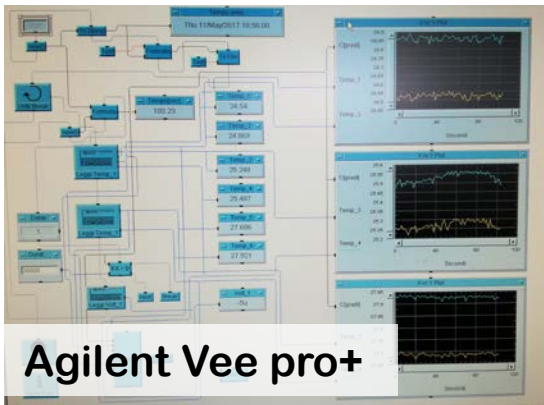
➤ RTD sensors to acquire water Inlet and Outlet temperature

➤ Ultrasonic flowmeter to control the water flow rate



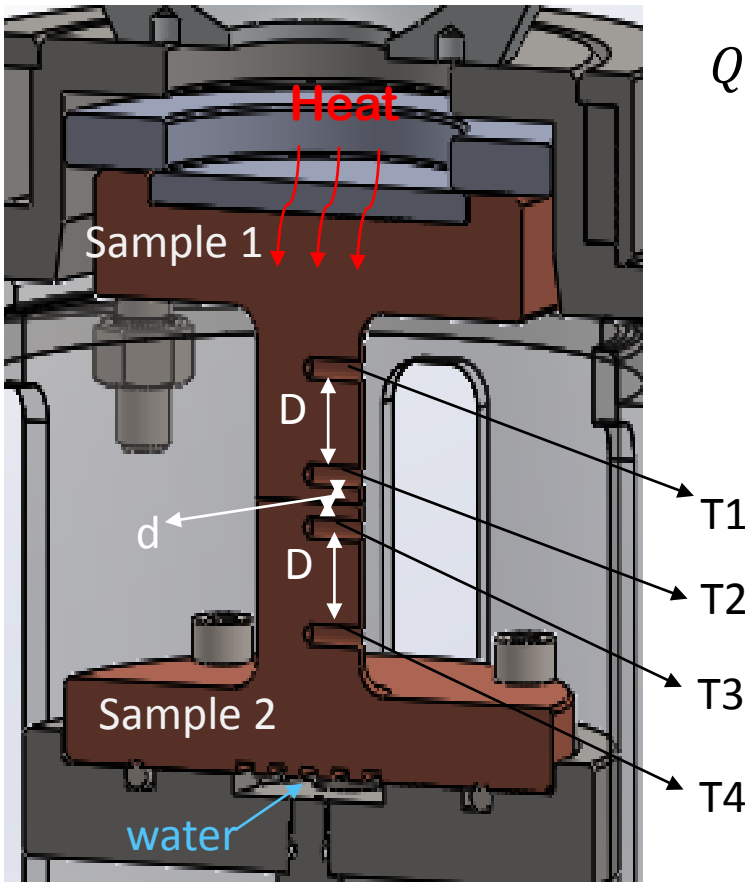
Data acquisition system

- Agilent for board sensors connection
- Program to record the data
 - Agilent Vee pro+
 - Labview
 - MatLab



- Calibration of T sensors in respect to calibrated TC
 - Error in Tc reading with Agilent vs channel

TCR estimation based on measured parameters



$$Q_1 = \frac{k \cdot A \cdot (T_1 - T_2)}{D} \qquad Q_2 = \frac{k \cdot A \cdot (T_3 - T_4)}{D}$$

$$Q_{water} = h_c \cdot A \cdot (T_{w out} - T_{w in})$$

$$\text{Power density} = \text{mean} \left\{ \frac{Q_1}{A} \dots \frac{Q_2}{A} \right\}$$

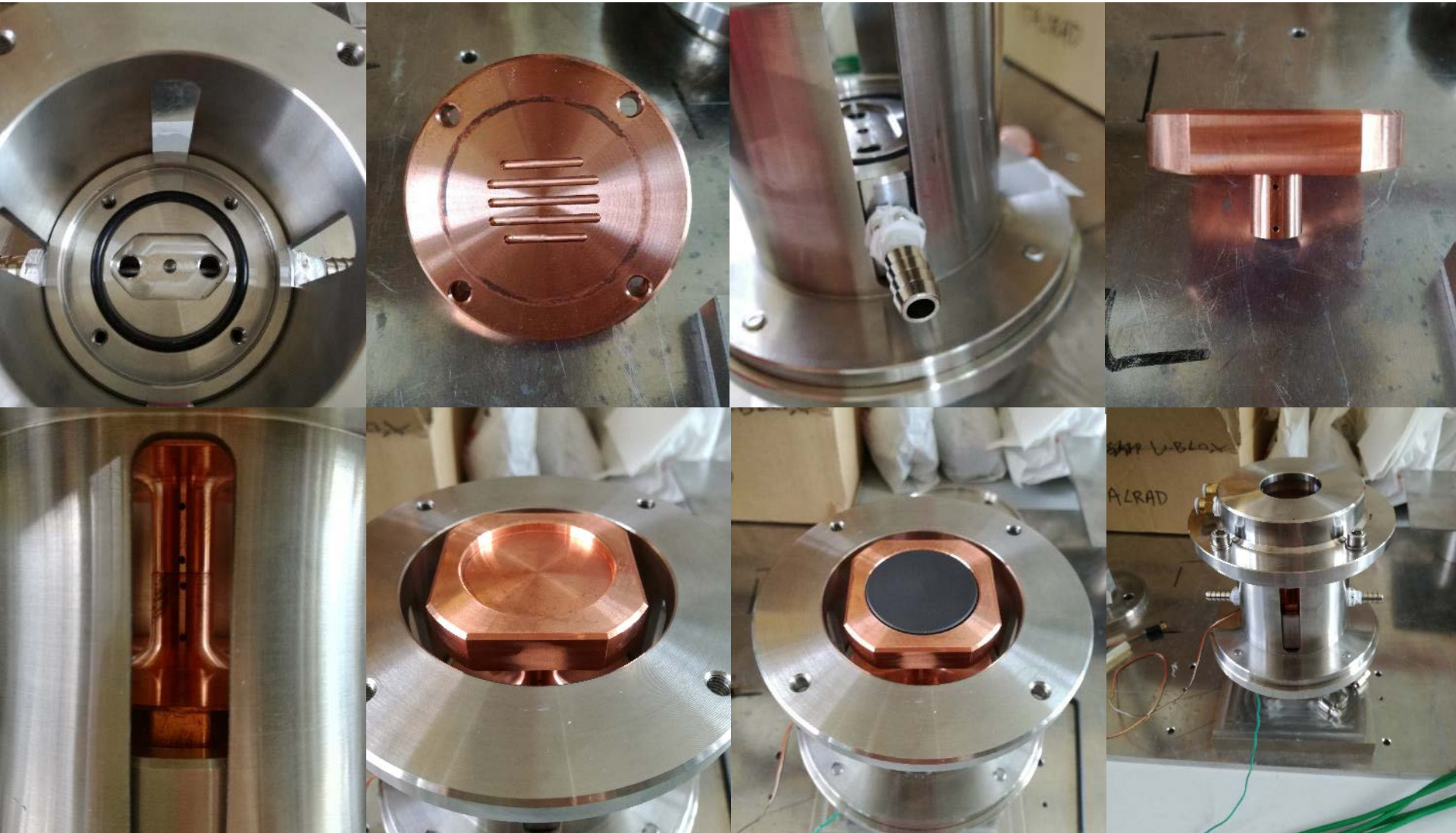
$$T_{cont 1} = T_2 - \left[\frac{(T_1 - T_2)}{D} \cdot d \right]$$

$$T_{cont 2} = T_3 + \left[\frac{(T_3 - T_4)}{D} \cdot d \right]$$

$$TCR = \frac{T_{cont 1} - T_{cont 2}}{\text{Power density}}$$

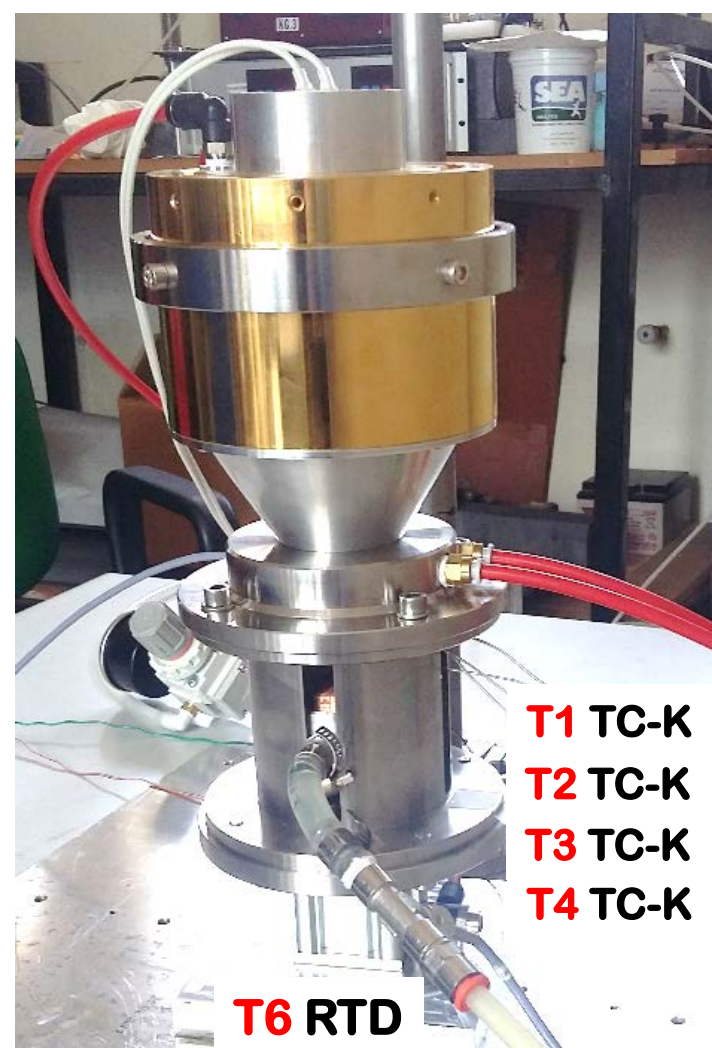
First experimental test

Samples and water cooling system assembling



First experimental test

Temperature sensors and assembled system



First experimental test

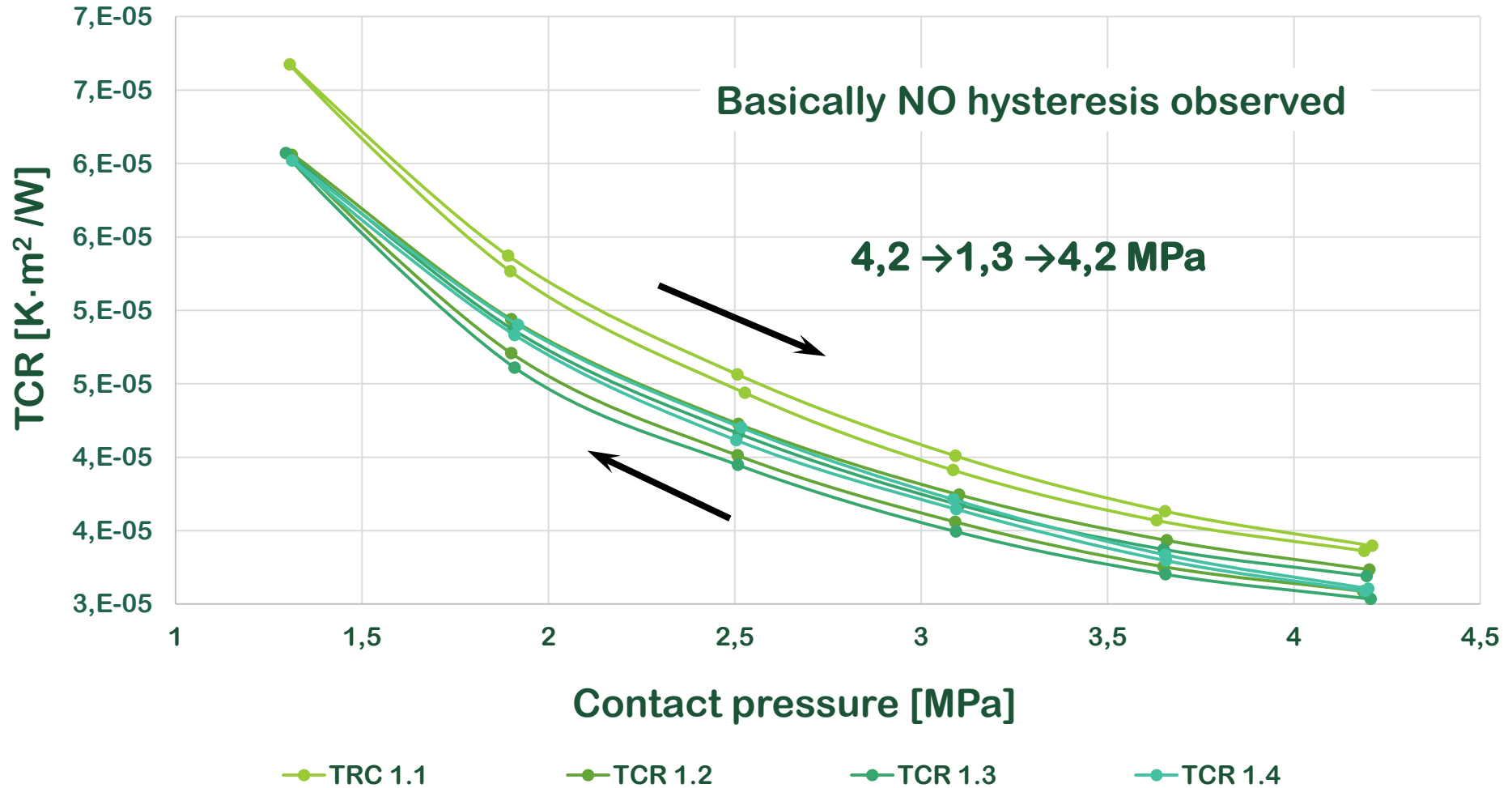
TCR vs Contact pressure

Conditions

Cooling of upper flange	NO
Collimator	YES
Lamp Voltage	50 V
Contact pressure [MPa]	4,2 → 1,3 → 4,2
Samples	Cu (standard turning $R_a \sim 3-5 \mu\text{m}$)
Water flow rate	2.4 l/min
Water inlet temperature	20 °C
Repetition	4 runs

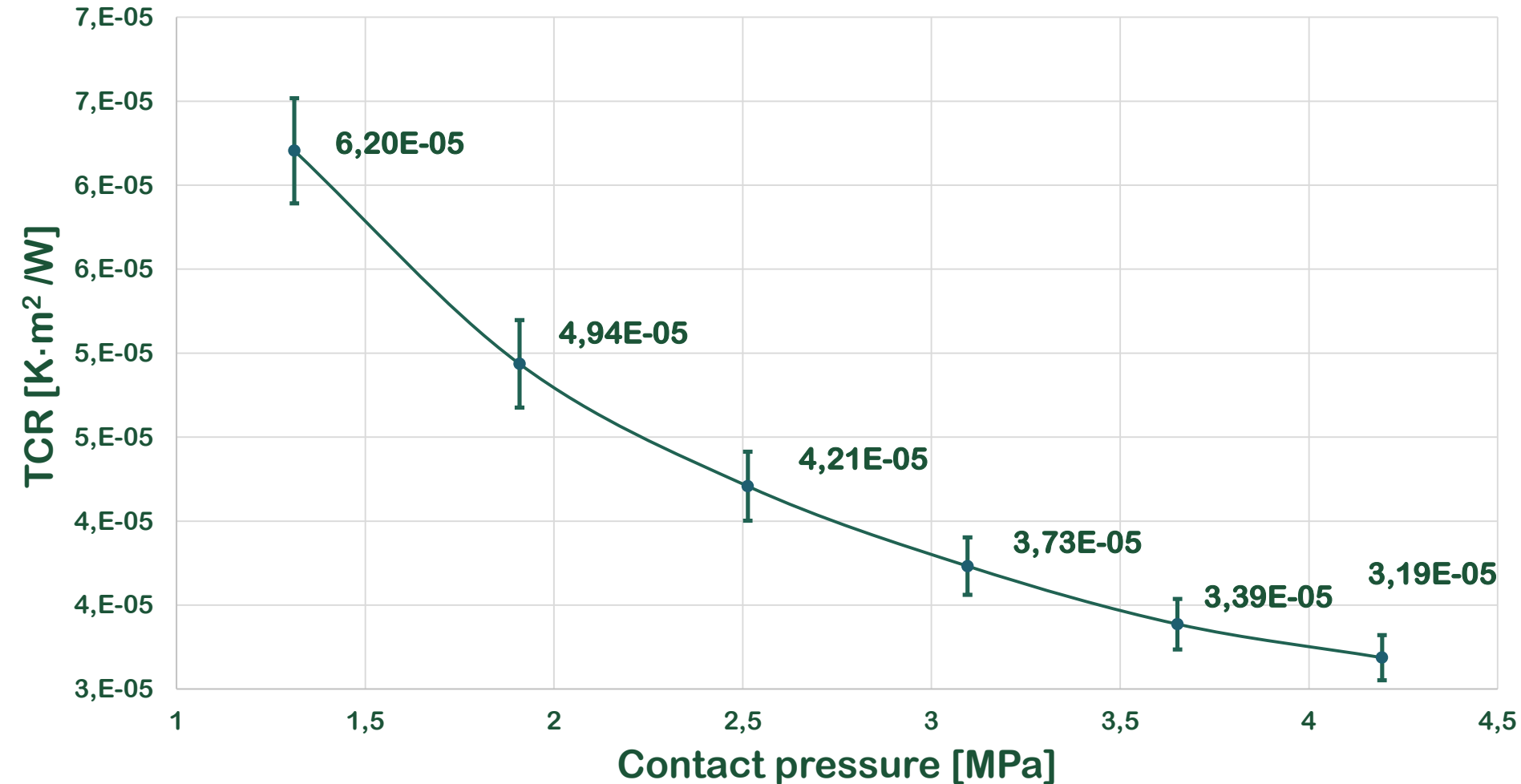
First experimental test

TCR vs Contact pressure trend



First experimental test

TCR vs Contact pressure trend



First experimental test

Comparison with analytical model

$$TCC = 1,55 k_s \left(\frac{m}{\sigma}\right) \left(\frac{\sqrt{2}p}{mE'}\right)^{0,94}$$

Working	Roughness R_a (μm)
Turning	0.2-6

TCC: thermal contact conductance [$\text{W m}^{-2} \text{K}^{-1}$]

k_s : 390 [$\text{W m}^{-1} \text{K}^{-1}$]

σ : $3 \cdot 10^{-6}$ [m] (standard turning surface finishing)

m : 0,19

p : $4,2 \cdot 10^6$ [Pa]

E' : $117 \cdot 10^9$ [Pa]

$$TCC = 1,7 \cdot 10^4 \text{ W m}^{-2} \text{ K}^{-1}$$

↓

$$TCR_{\text{model}} = 5,8 \cdot 10^{-5} \text{ m}^2 \text{ K W}^{-1}$$

$$TCR_{\text{exp}} = 3..4 \cdot 10^{-5} \text{ m}^2 \text{ K W}^{-1}$$

Good matching between theoretical and experimental values

Thermal contact resistance at interface

Expected values at fixed surface roughness

Estimation of TCR vs Contact pressure

Cu-Cu, 0.1 μm , 1kW/cm ²		
Pressure [MPa]	TCR [K m ² W ⁻¹]	ΔT expected [K]
4	2,0e-6	20
3	2,6e-6	26
2	3,8e-6	38
1	7,2e-6	72
0.5	1,4e-5	139

Taking into account a standard lapping surface finishing ($R_a \sim 0.1 \mu\text{m}$) the design specs may be achieved \rightarrow minimal interface temperature drop.

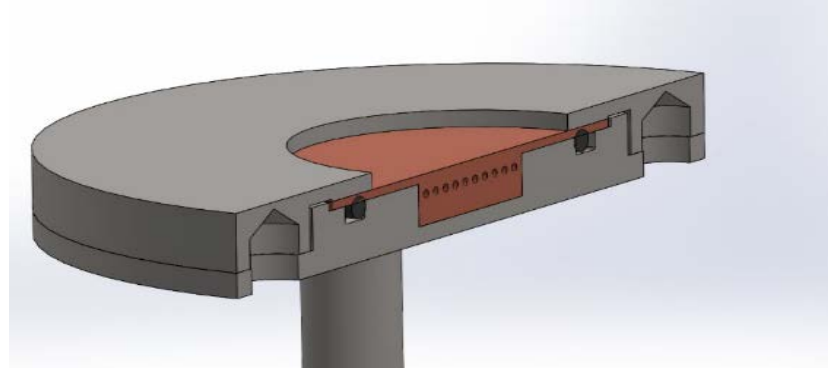
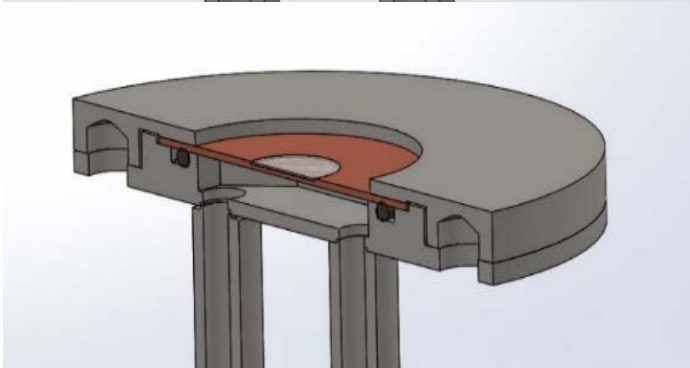
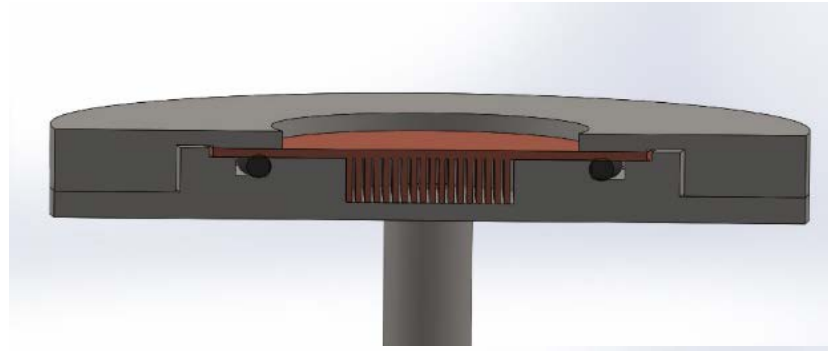
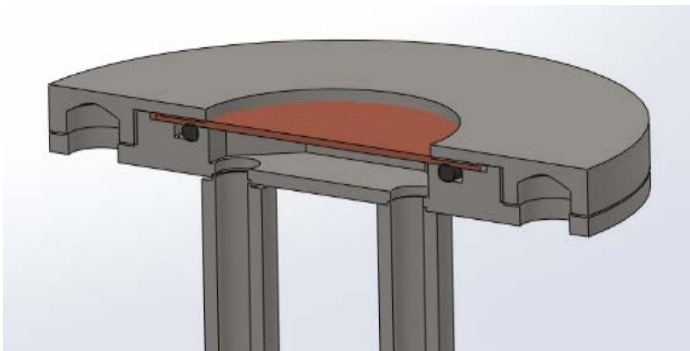
Future plan

- **TCR vs roughness (lapped, standard turning, mirror-like)**
- **+ Al samples**
- **Oxidized surfaces**
- **Use of protective coating (Au)**

Future plan

Additional prospective

- Test particular cooling chamber system geometry (lamella, microchannel, non-standard geometries prepared with Additional Manufacturing)



**Thank you for your
kind attention!**